



Docket No.: SON-2920

(PATENT)

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hironori IBUSUKI

Confirmation No.: 1986

Application No.: 10/780,667

Art Unit: 1756

Filed: February 19, 2004

Examiner: Not Yet Assigned

For: EXPOSURE PATTERN OR MASK AND

INSPECTION METHOD AND

MANUFACTURE METHOD FOR THE SAME

## **STATUS INQUIRY**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Please inform the undersigned when the initial Action on the merits of the aboveidentified application may be expected. The application has now been pending 15 months without an action on the merits.

Date: May 10, 2005

Respectfully submitted,

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